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PATENT

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

EXPRESS MAIL NO. EV809338217US

Appl No.	:	N/A	Confirmation No. N/A
Applicant	:	Nam Hun Kim	
Filed	:	September 22, 2006	
Title	:	PLASMA CHAMBER HAVING PLASMA SOURCE COIL AND METHOD FOR ETCHING THE WAFER USING THE SAME	
TC/A.U.	:	N/A	
Examiner	:	N/A	
Docket No.	:	58409/N305	
Customer No.	:	23363	

## PRELIMINARY AMENDMENT

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Post Office Box 7068  
Pasadena, CA 91109-7068  
September 22, 2006

Commissioner:

Prior to examination, please amend the above-identified application as follows:

**Amendments to the Specification** begin on page 2 of this paper.

**Remarks/Arguments** begin on page 3 of this paper.

**Appendix** an Abstract of the Disclosure, on a separate page, is attached following page 3 of this paper.